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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of : **Confirmation No. 9257**
Tetsuji TOGAWA et al. : Attorney Docket No. 2005_0993A
Serial No. 10/539,245 : Group Art Unit 3723
Filed March 29, 2006 : Examiner Maurina T. Rachuba
SUBSTRATE HOLDING MECHANISM, : **Mail Stop AMENDMENT**
SUBSTRATE POLISHING APPARATUS
AND SUBSTRATE POLISHING METHOD

AMENDMENT

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

Responsive to the Office Action mailed April 11, 2007, please amend the above-identified application as follows: